

REPLACEMENT SHEET

Title: SYSTEM AND METHOD FOR PROCESS MONITORING OF POLYSILICON ETCH
Inventor(s): Bhanwar Singh, *et al.*; Serial No.: 09/973,231

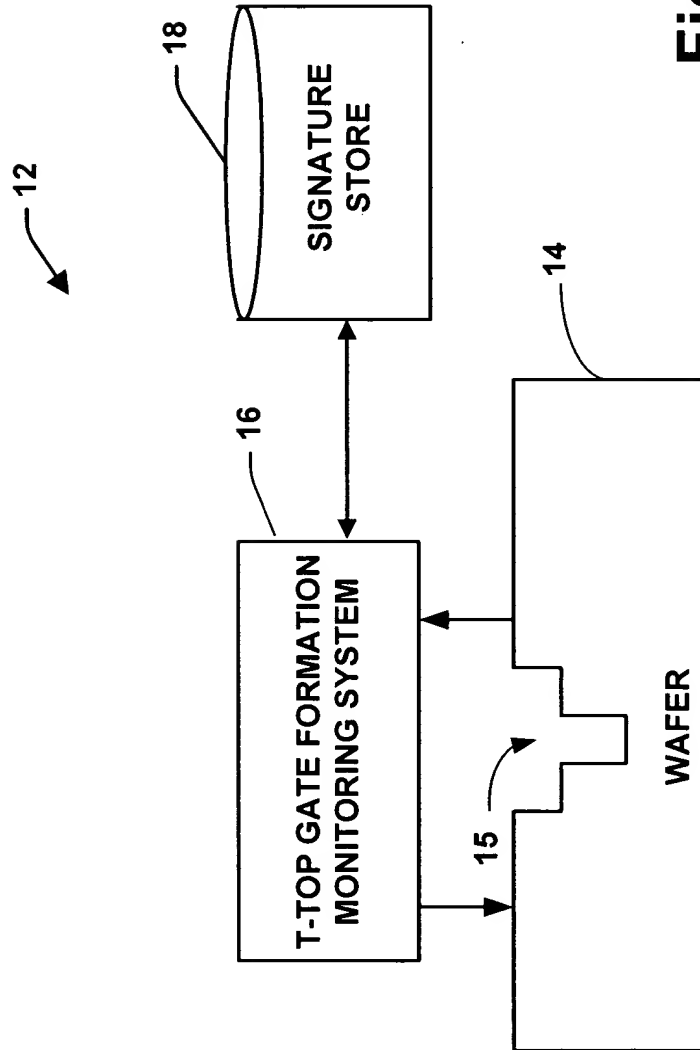


Fig. 1

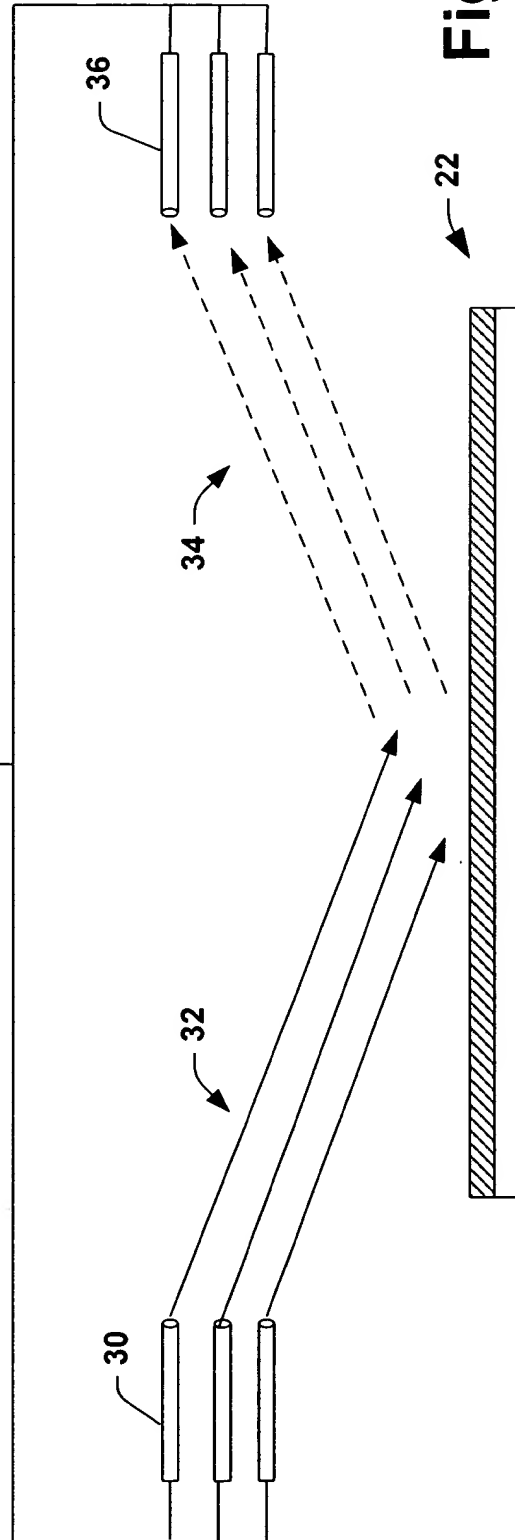
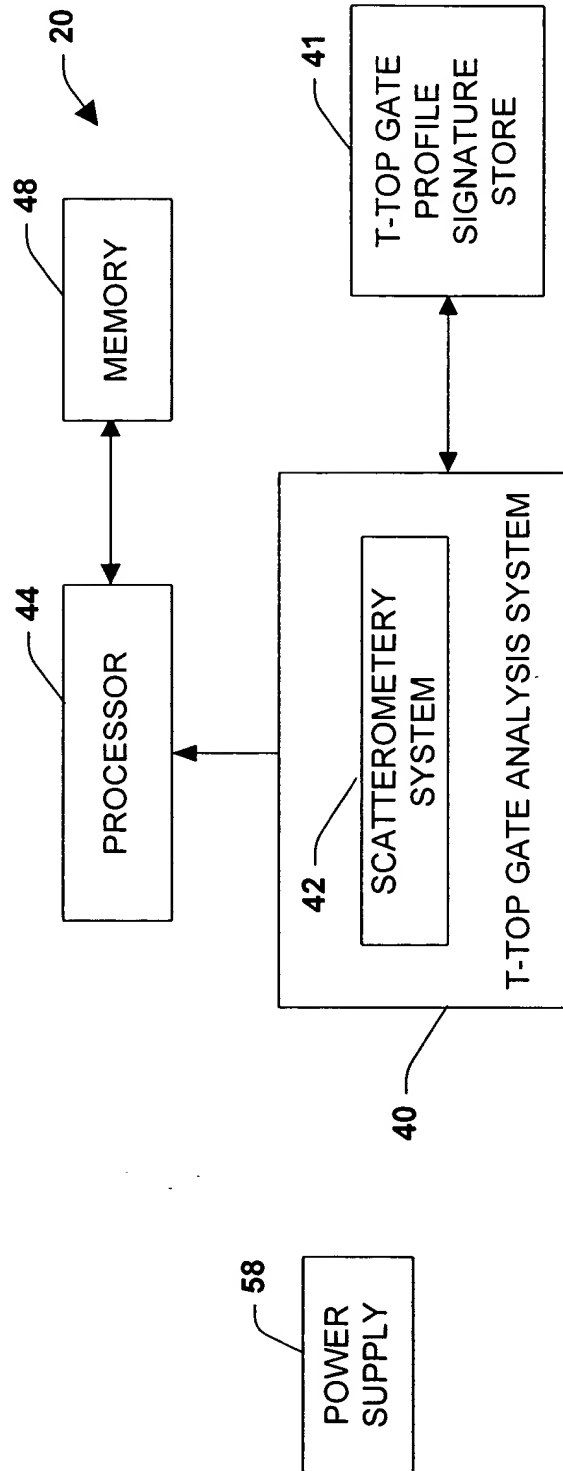


Fig. 2

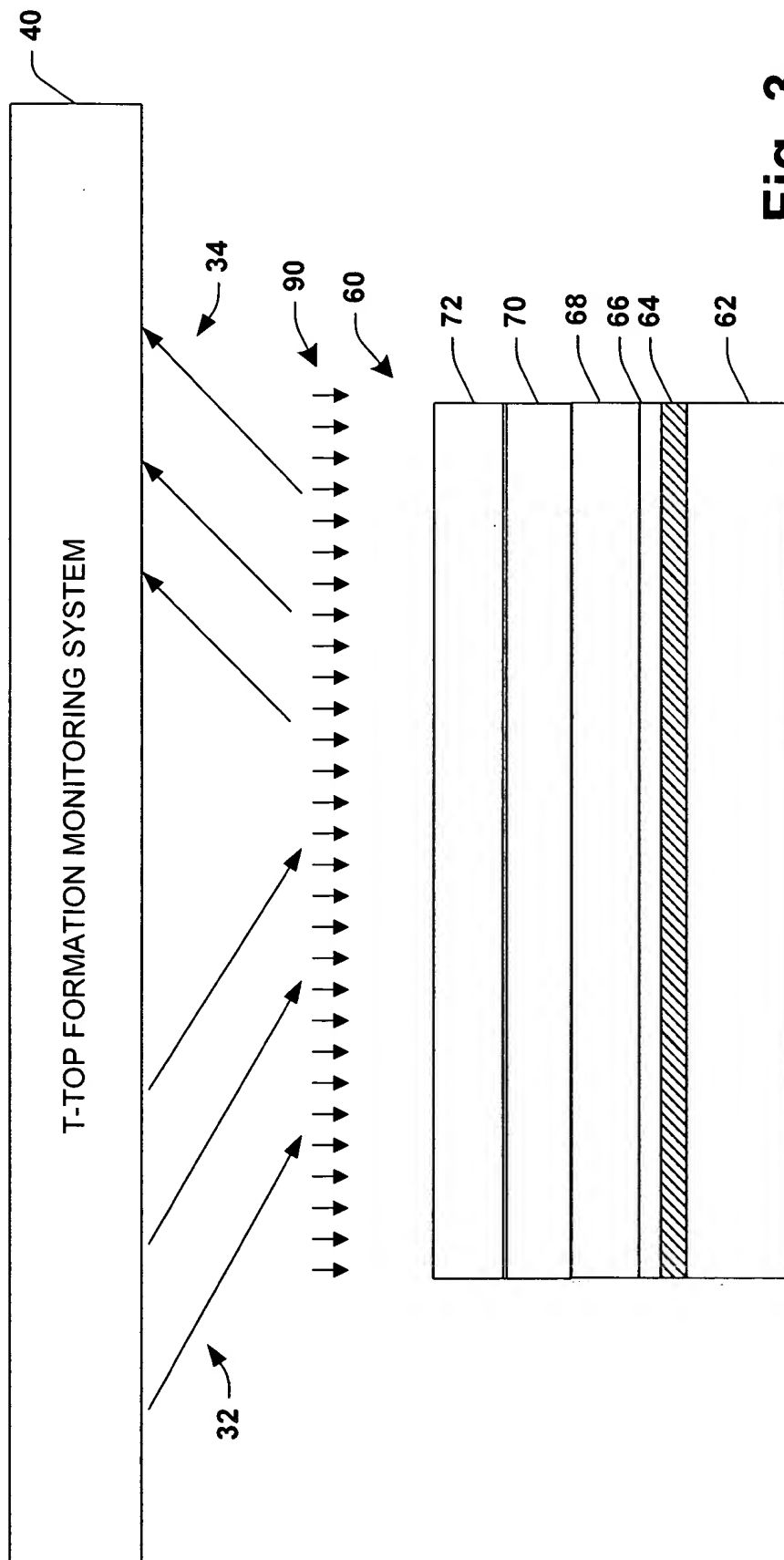


Fig. 3

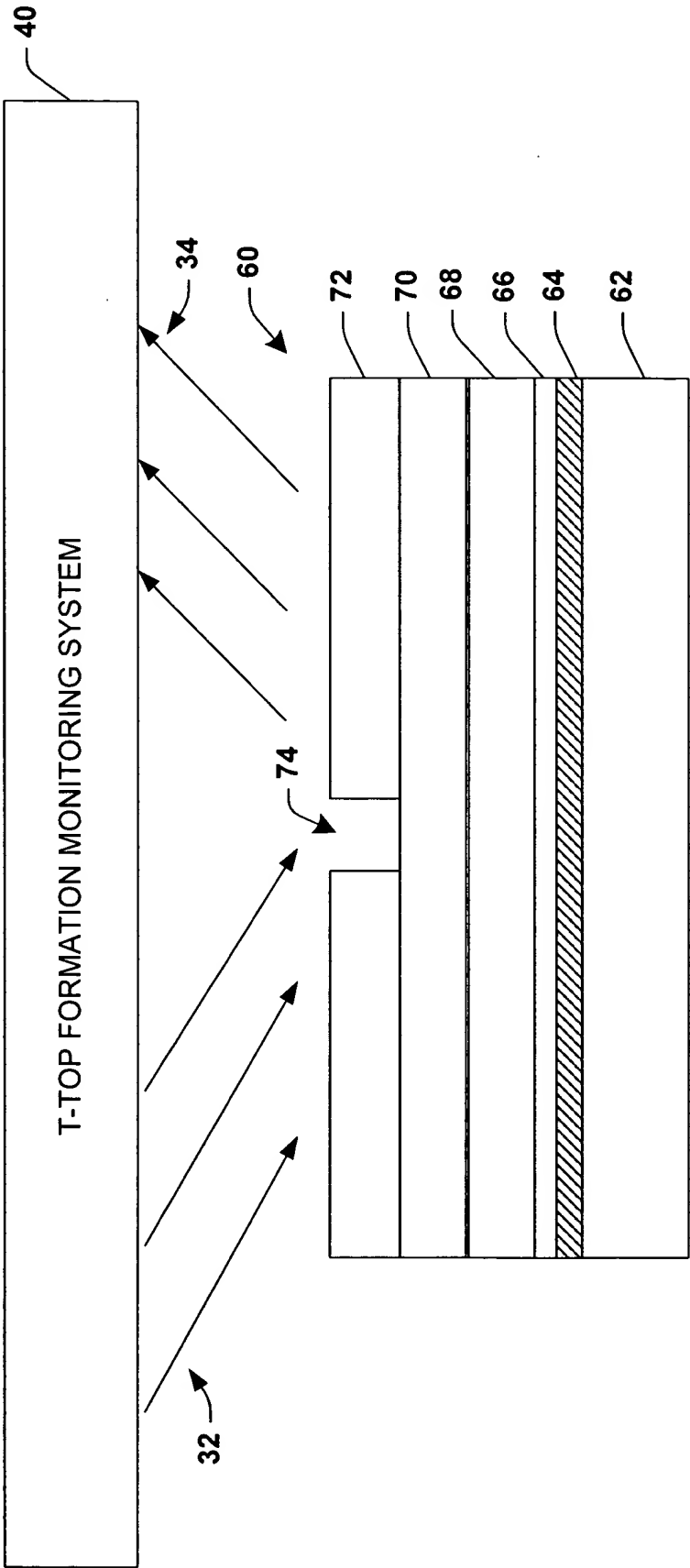


Fig. 4



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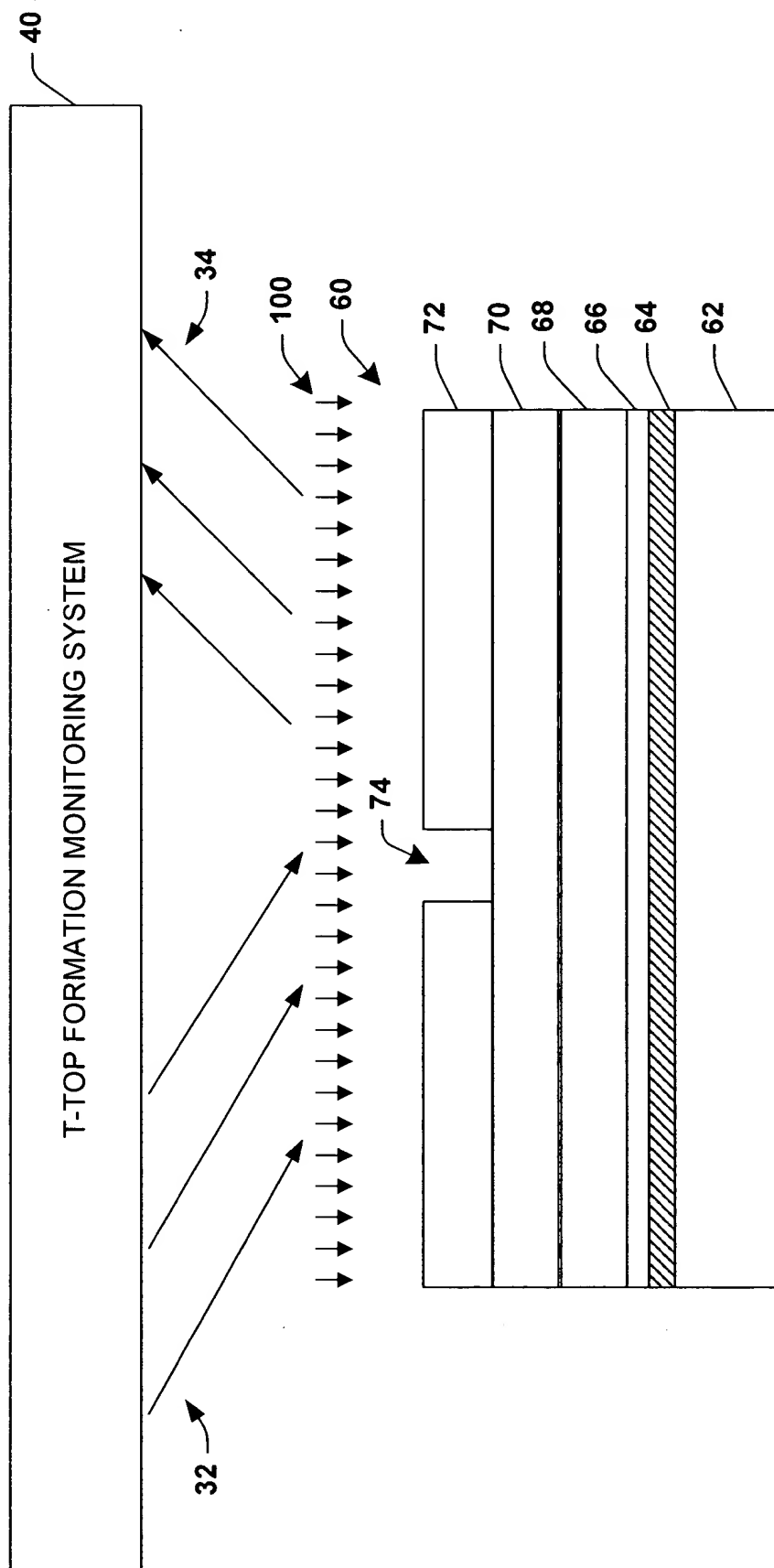


Fig. 5

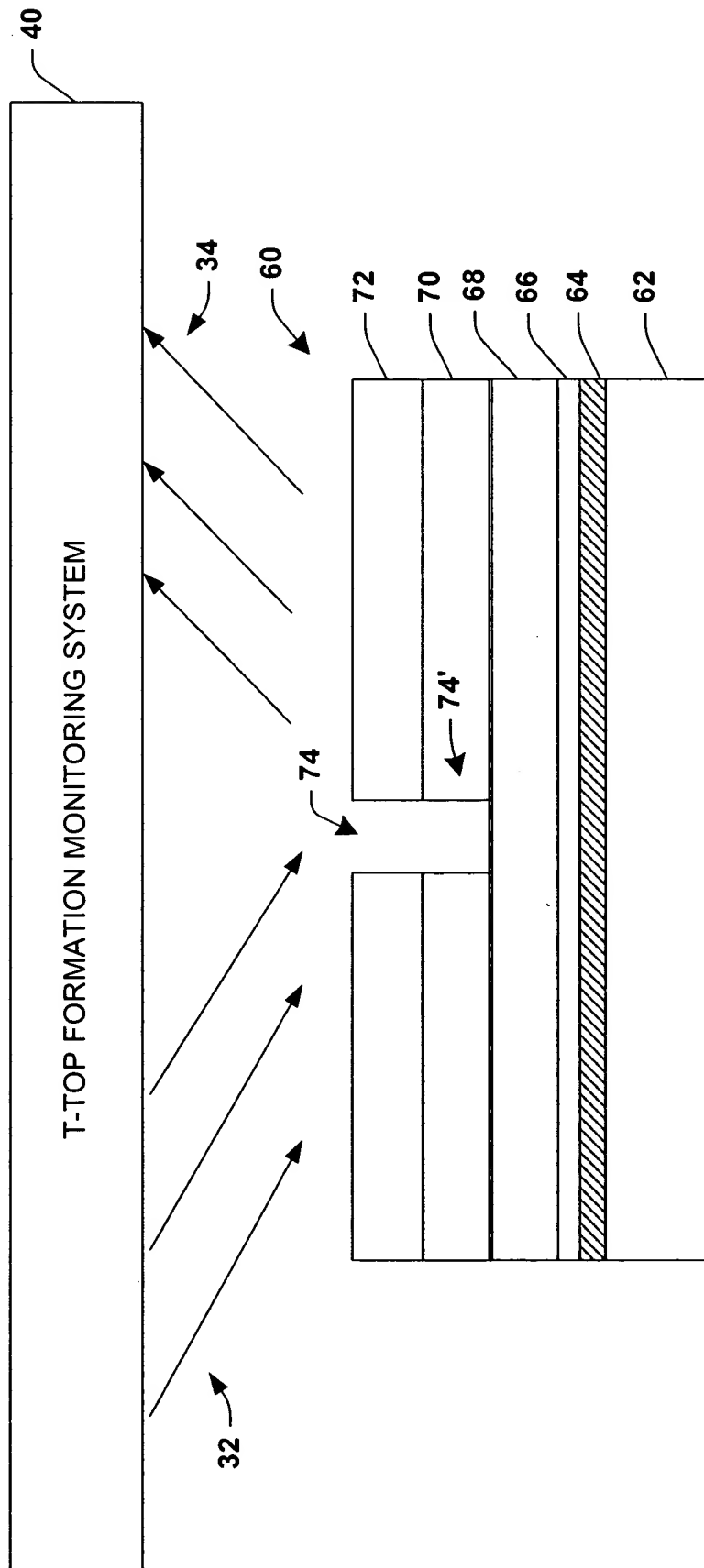


Fig. 6



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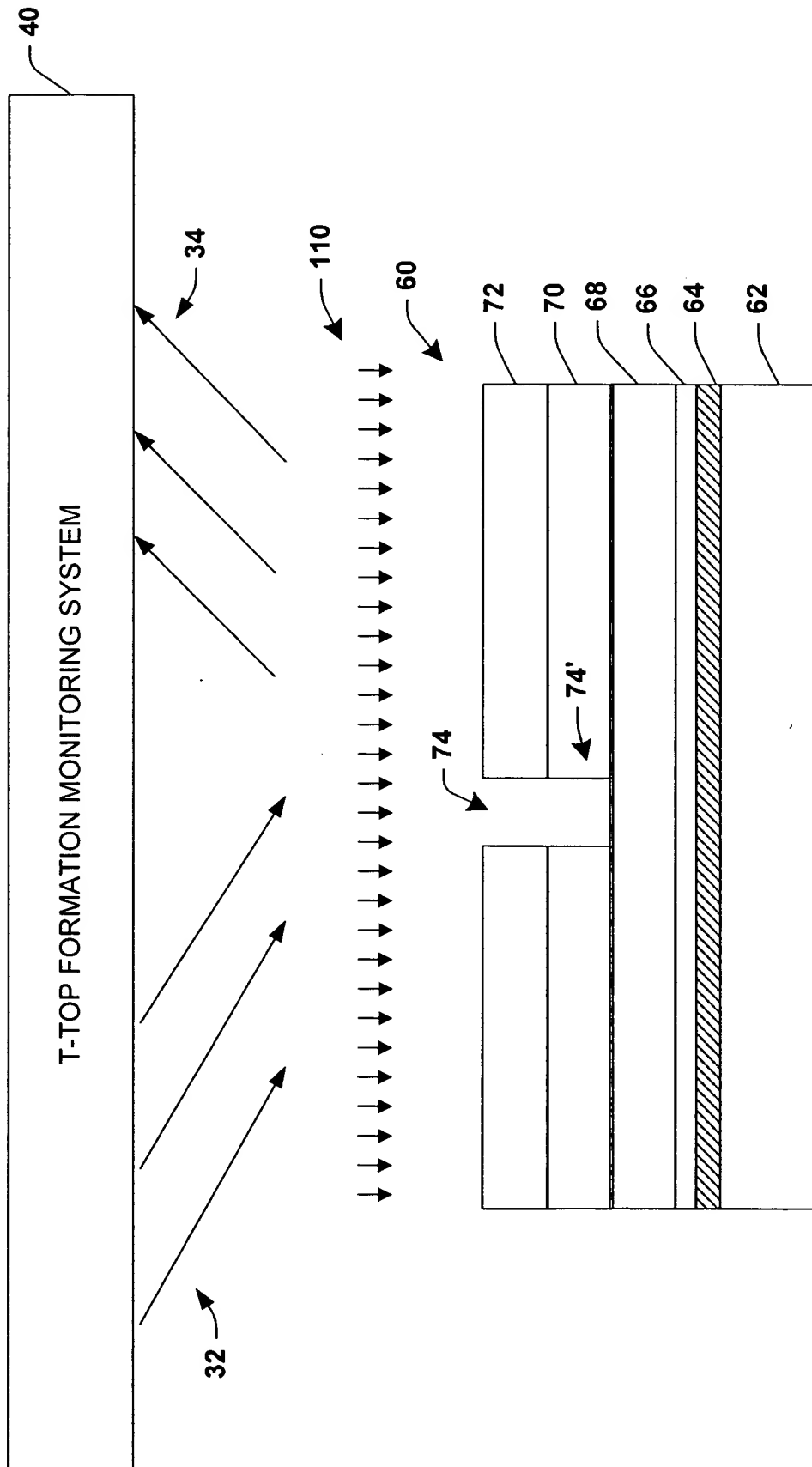


Fig. 7



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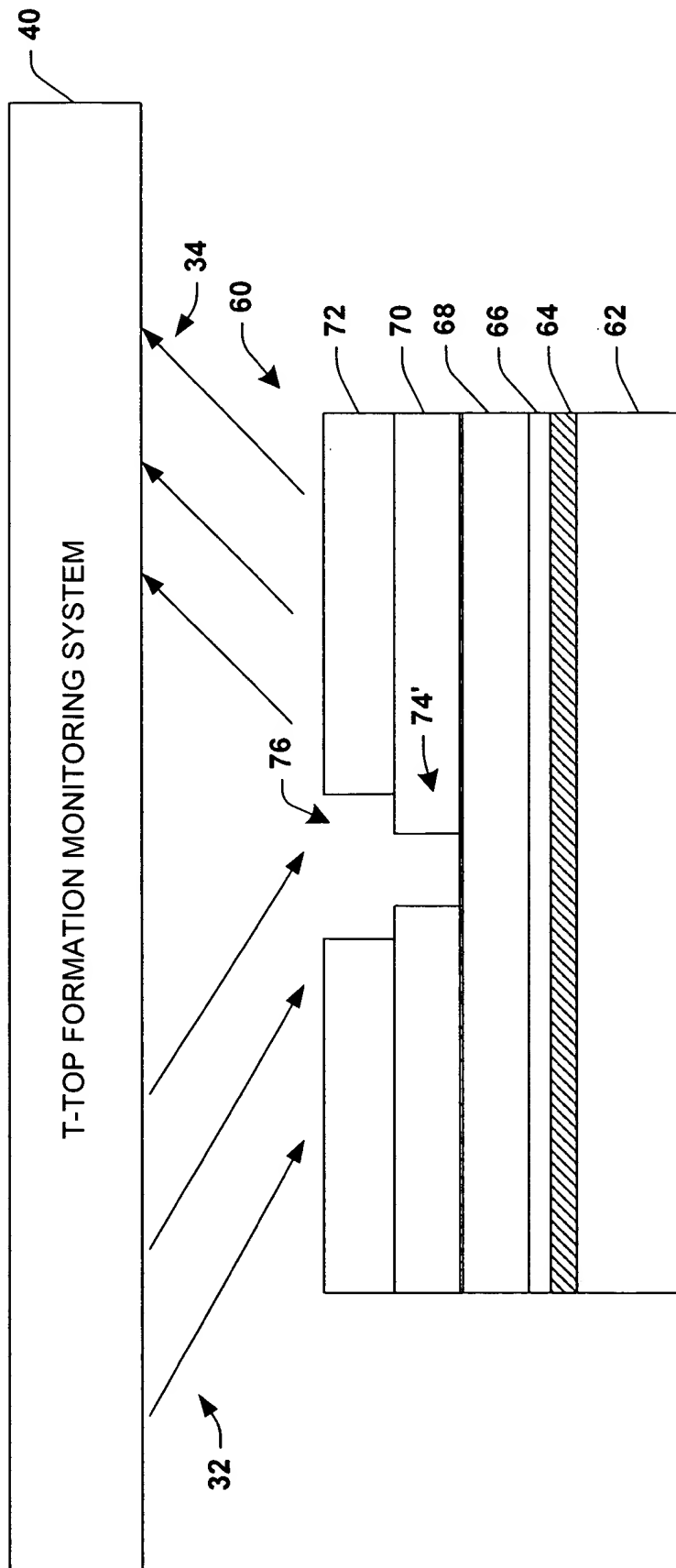


Fig. 8



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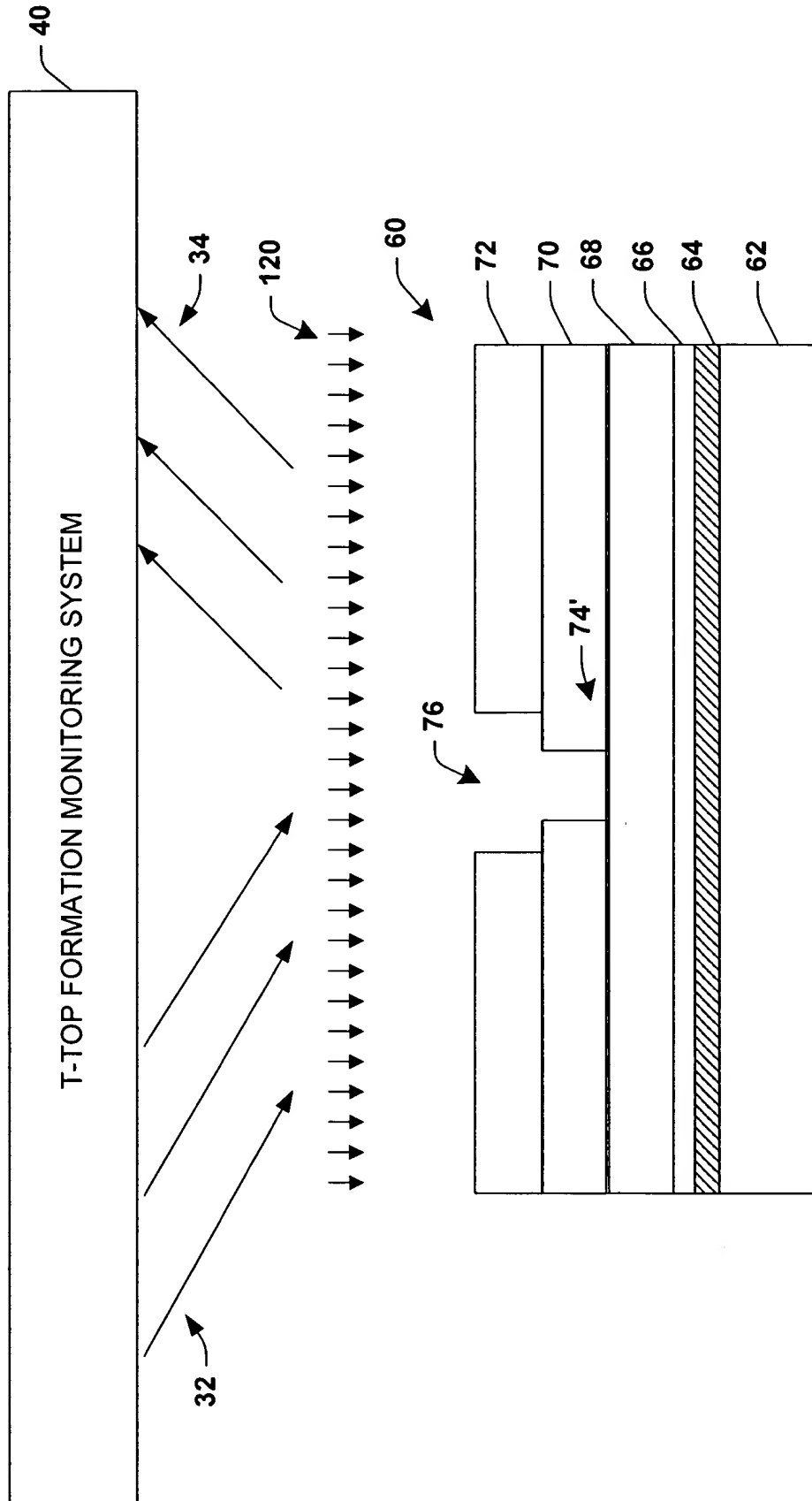


Fig. 9

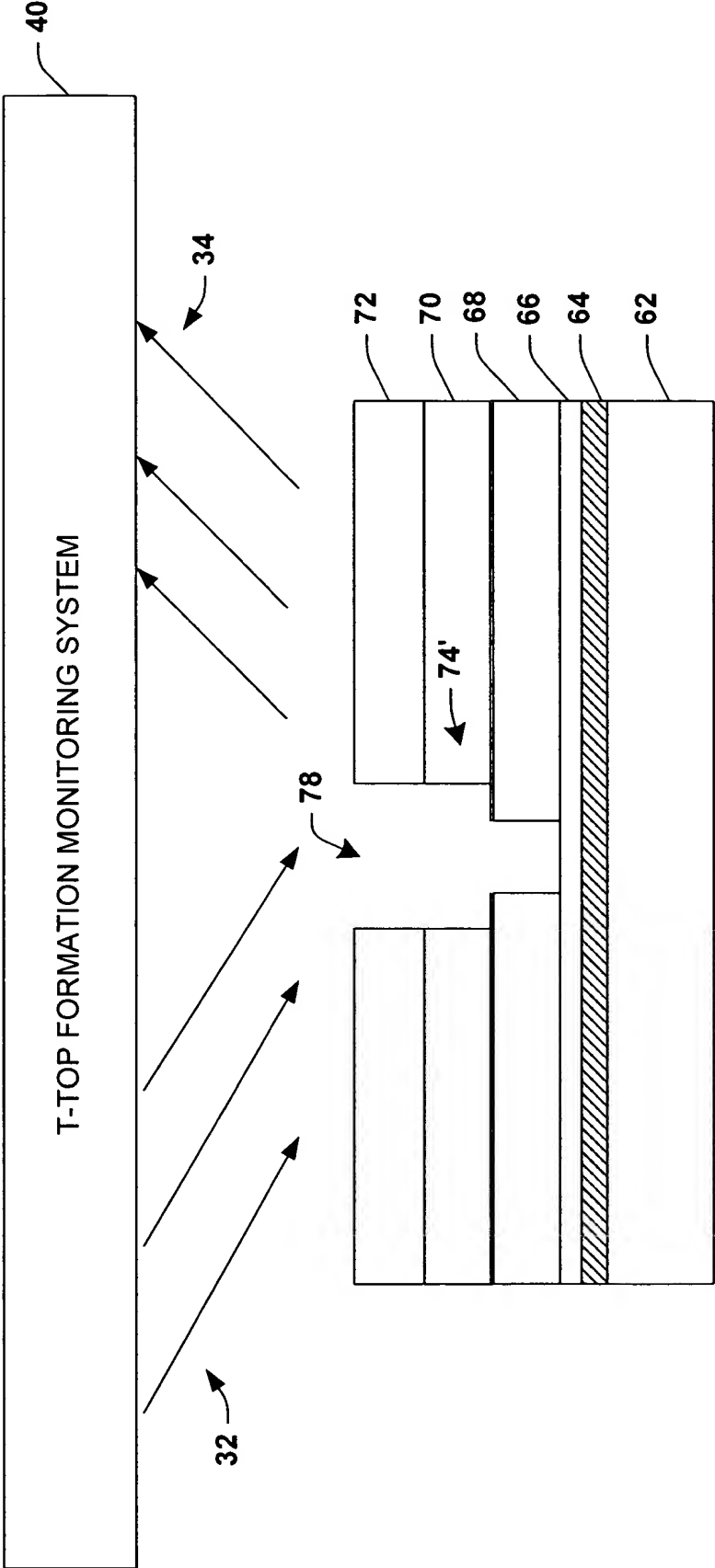


Fig. 10

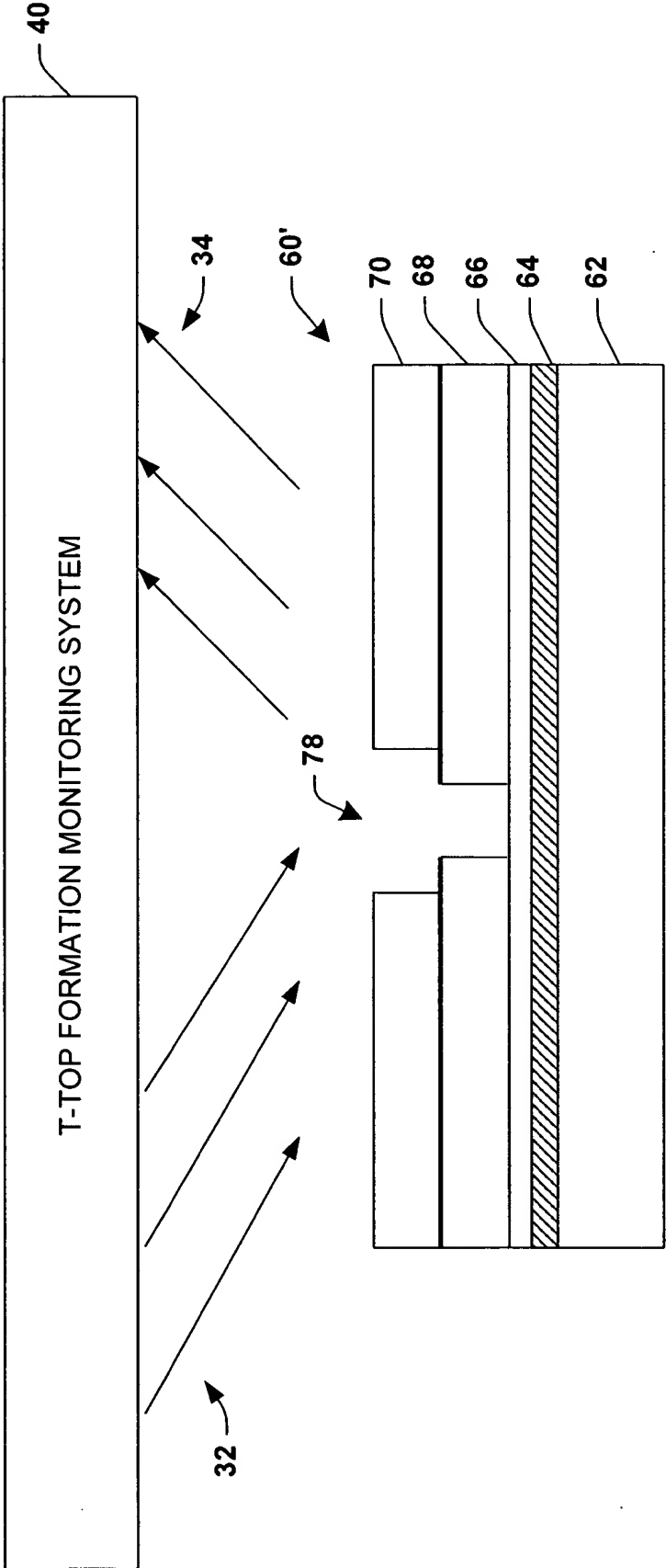


Fig. 11

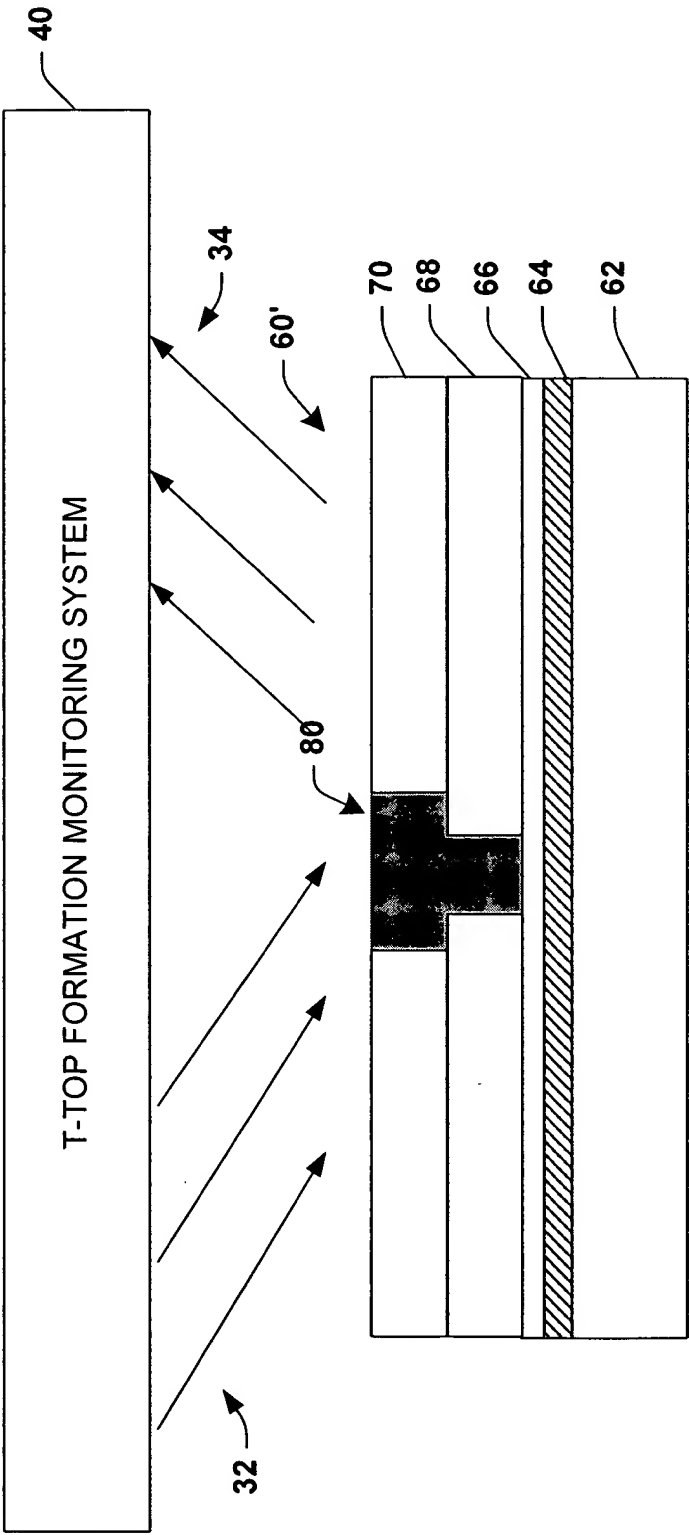


Fig. 12



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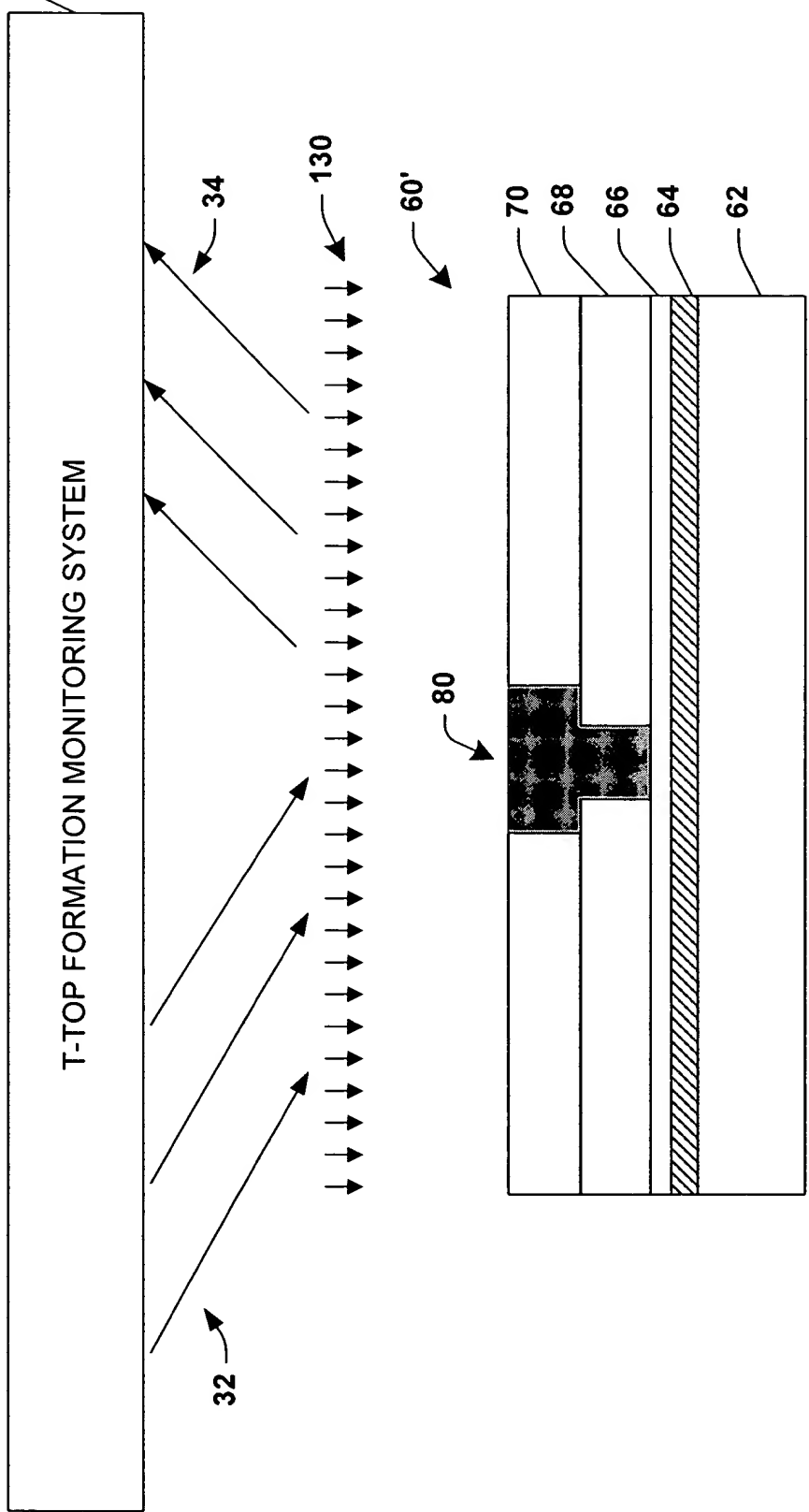


Fig. 13



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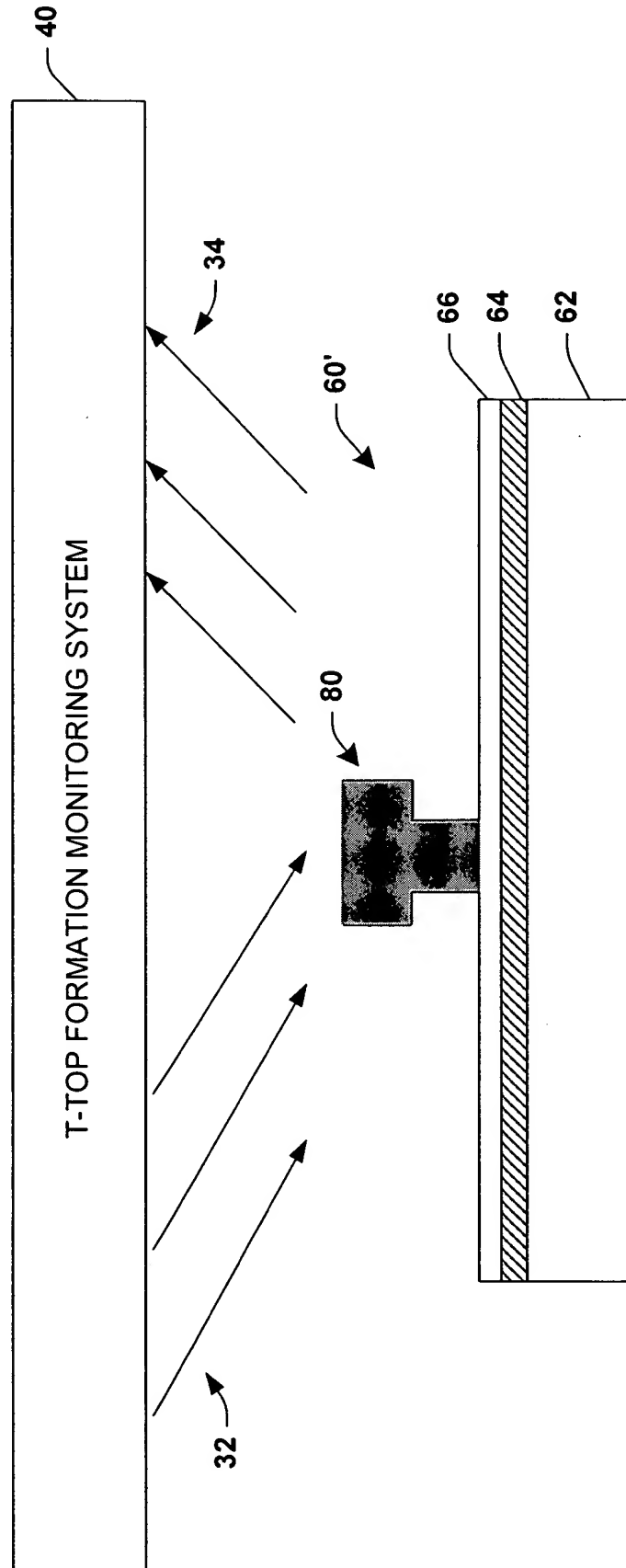


Fig. 14

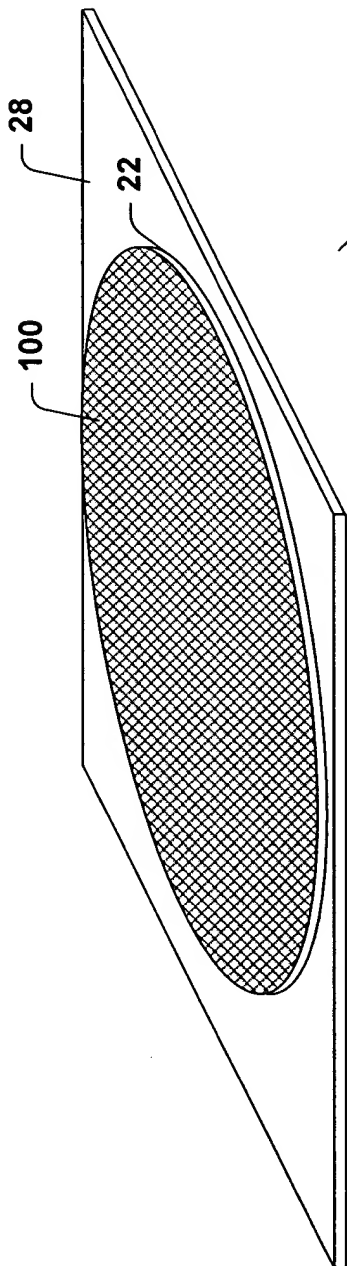


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Fig. 15



	X ₁	X ₂	X ₃	X ₄	X ₅	X ₆	X ₇	X ₈	X ₉	X ₁₀	X ₁₁	X ₁₂
Y ₁	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₂	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₃	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₄	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₅	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₆	T _A	T _A	T _A	T _A	T _A	T _A	T _U	T _A	T _A	T _A	T _A	T _A
Y ₇	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₈	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₉	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₁₀	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₁₁	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A
Y ₁₂	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A	T _A

Fig. 17

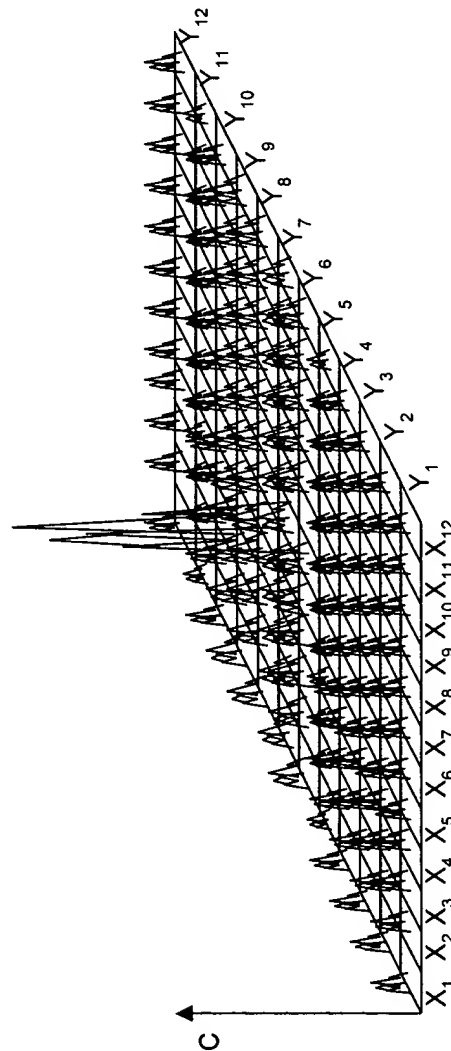


Fig. 16

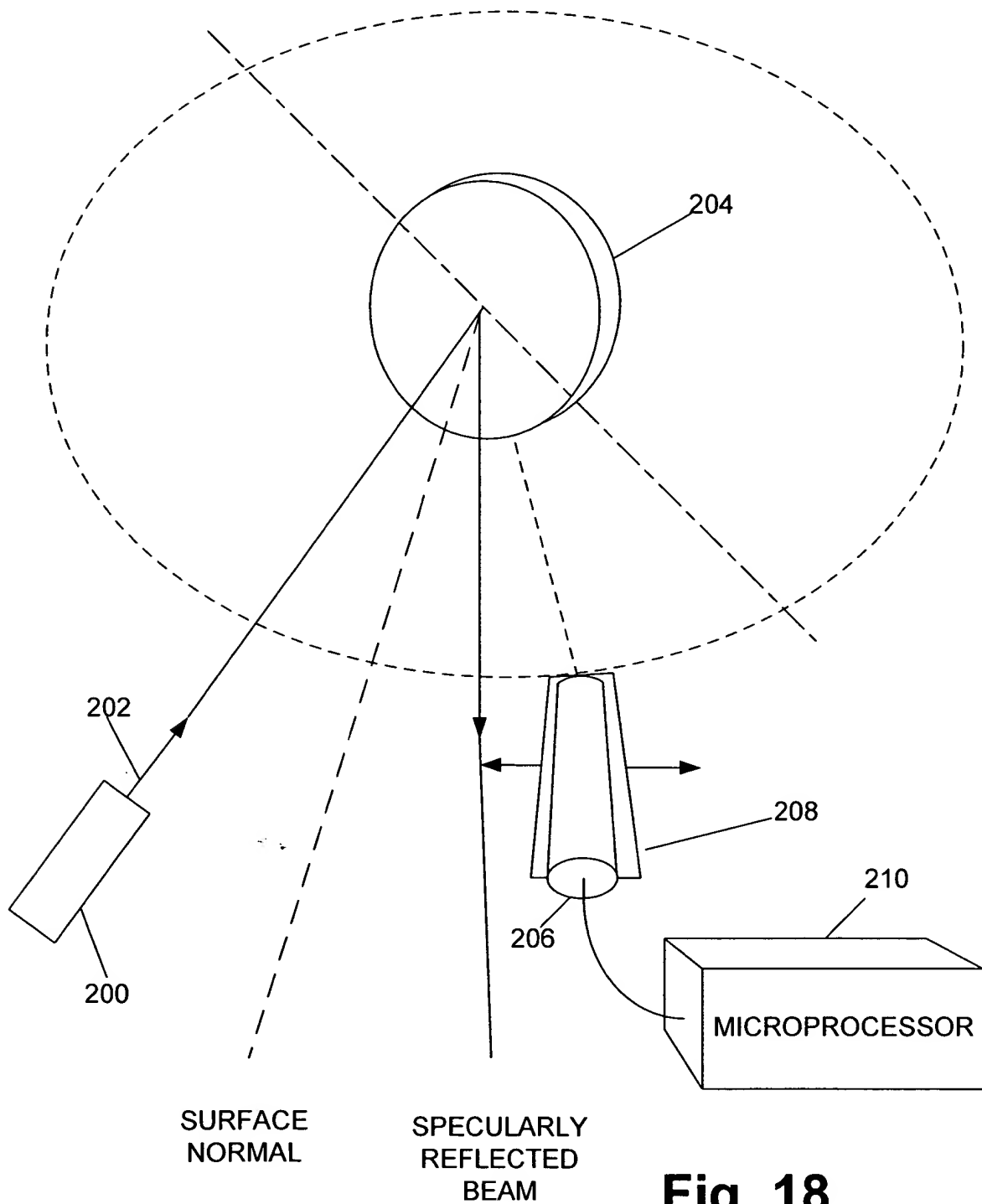
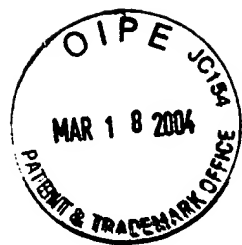


Fig. 18



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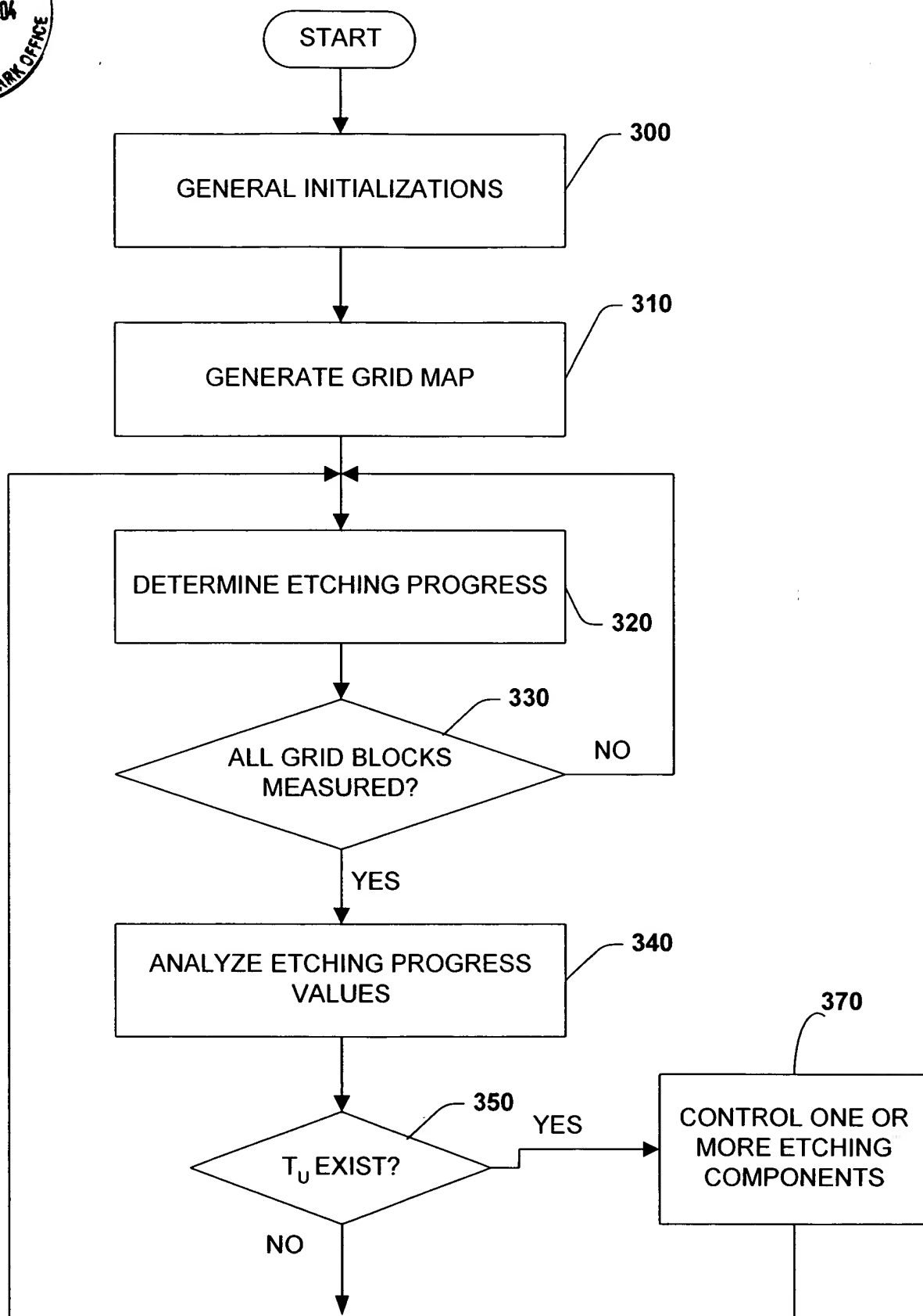


Fig. 19

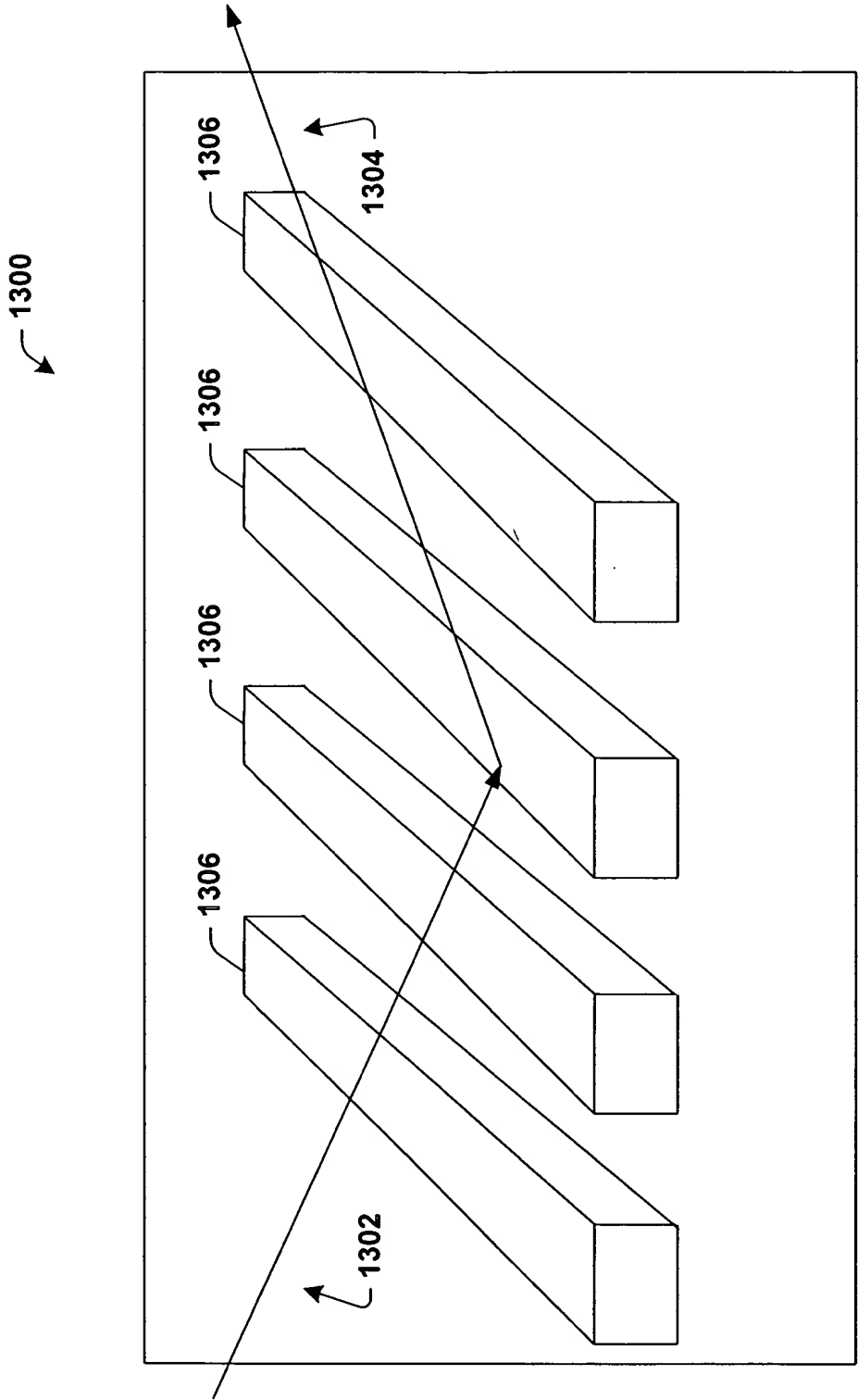


Fig. 20

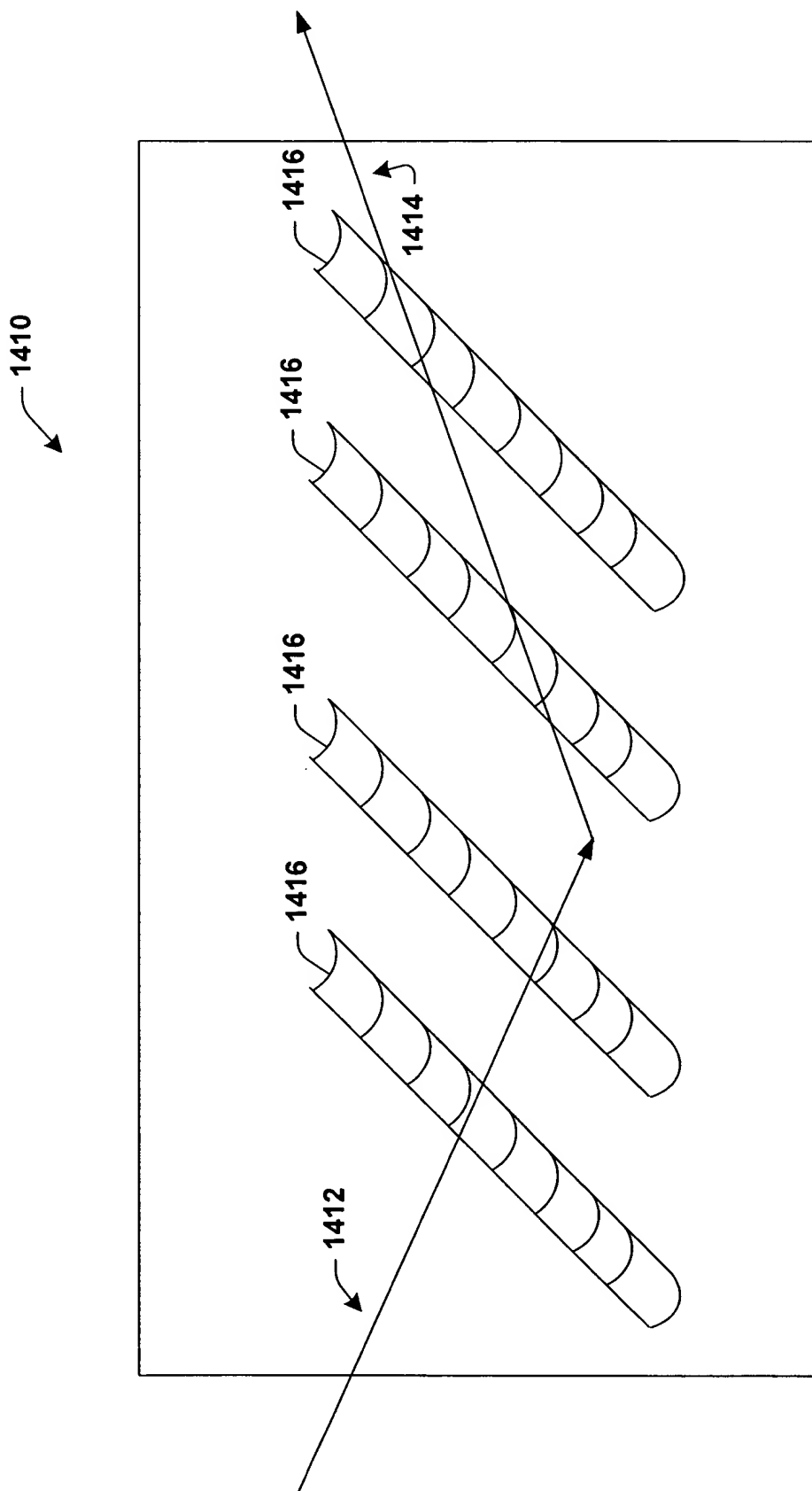
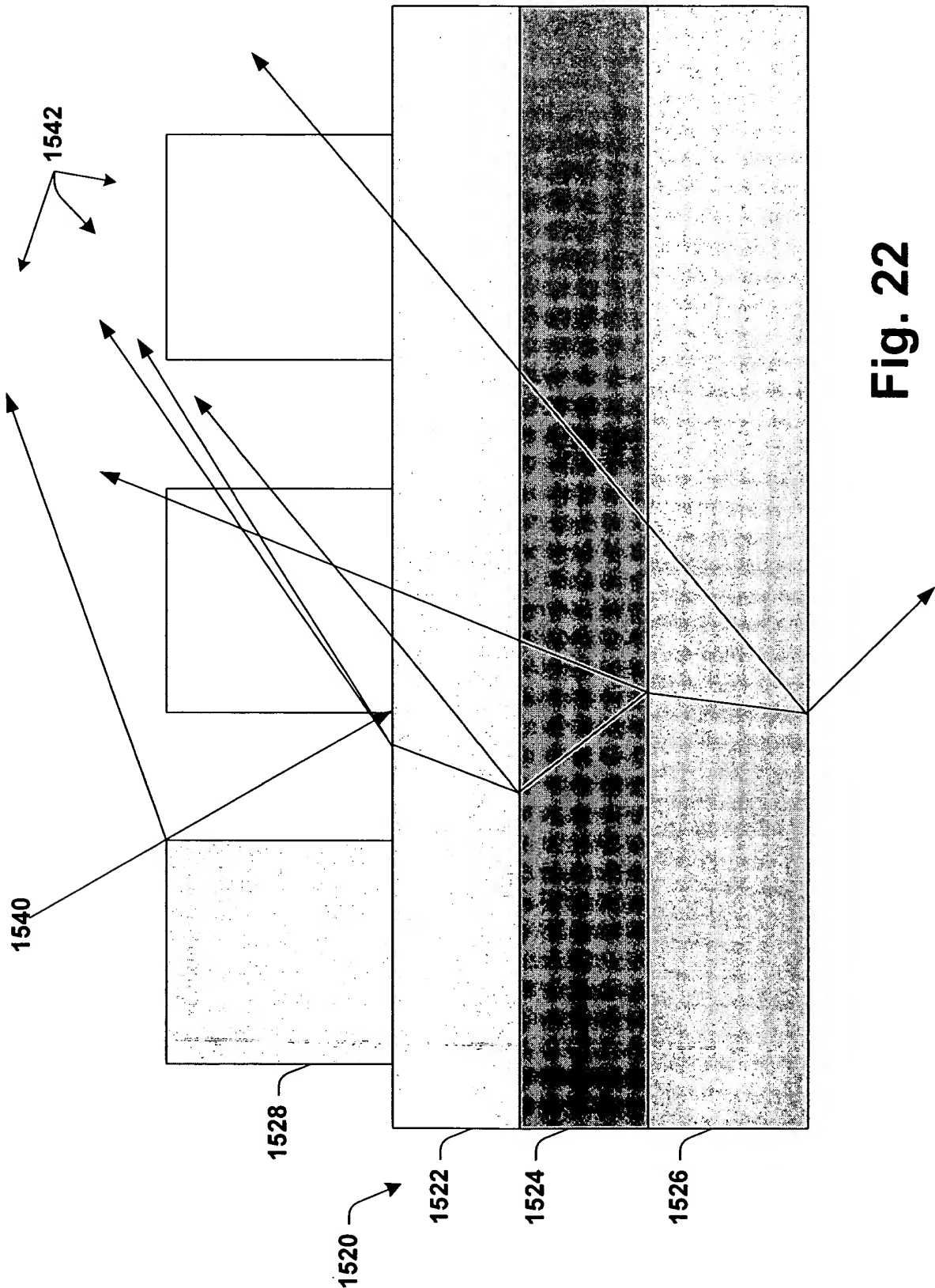
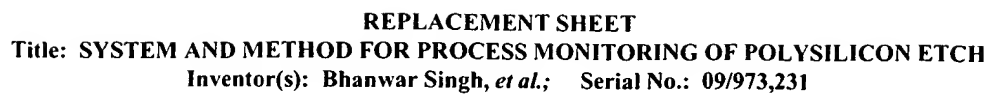


Fig. 21





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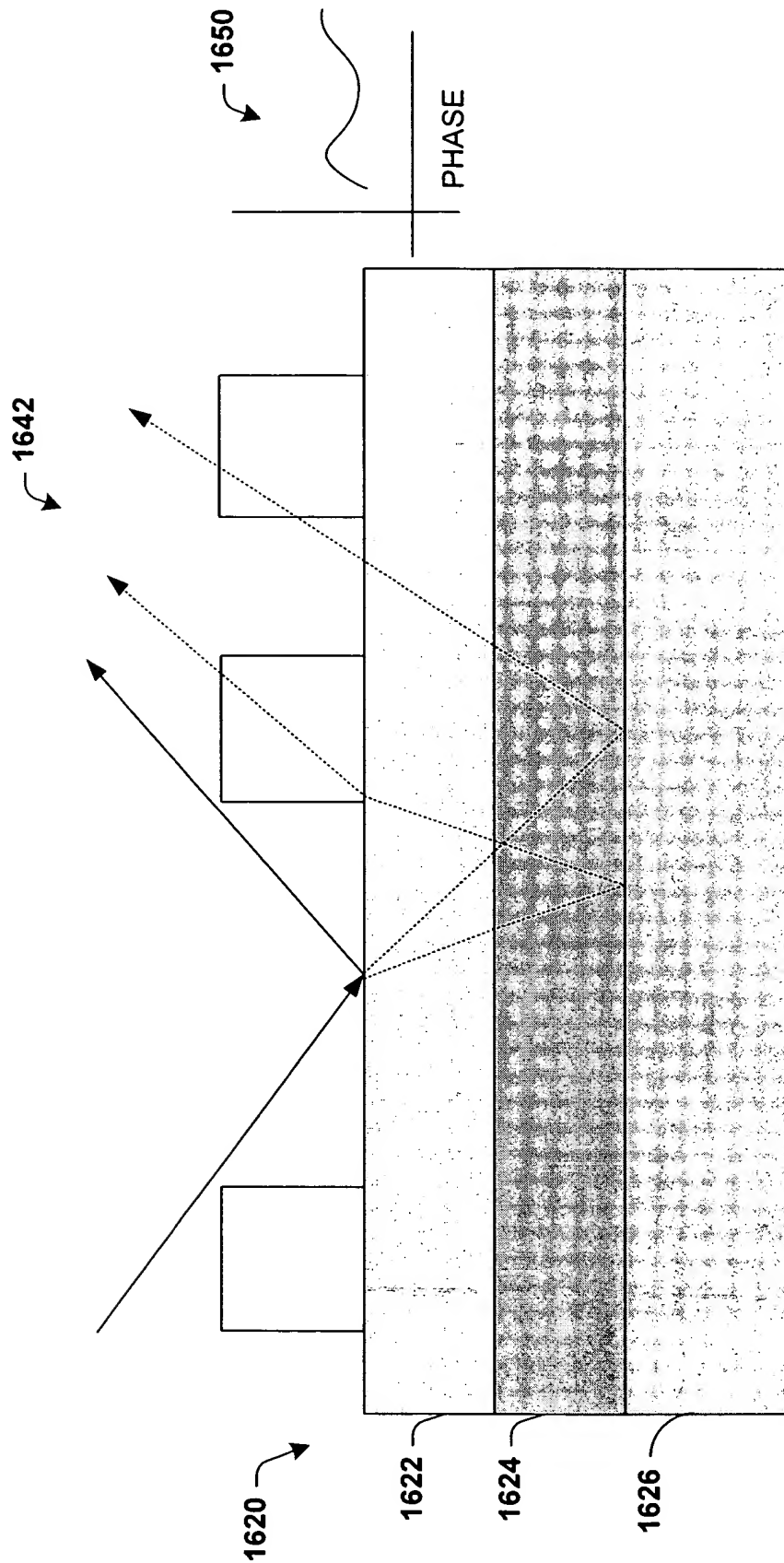


Fig. 23



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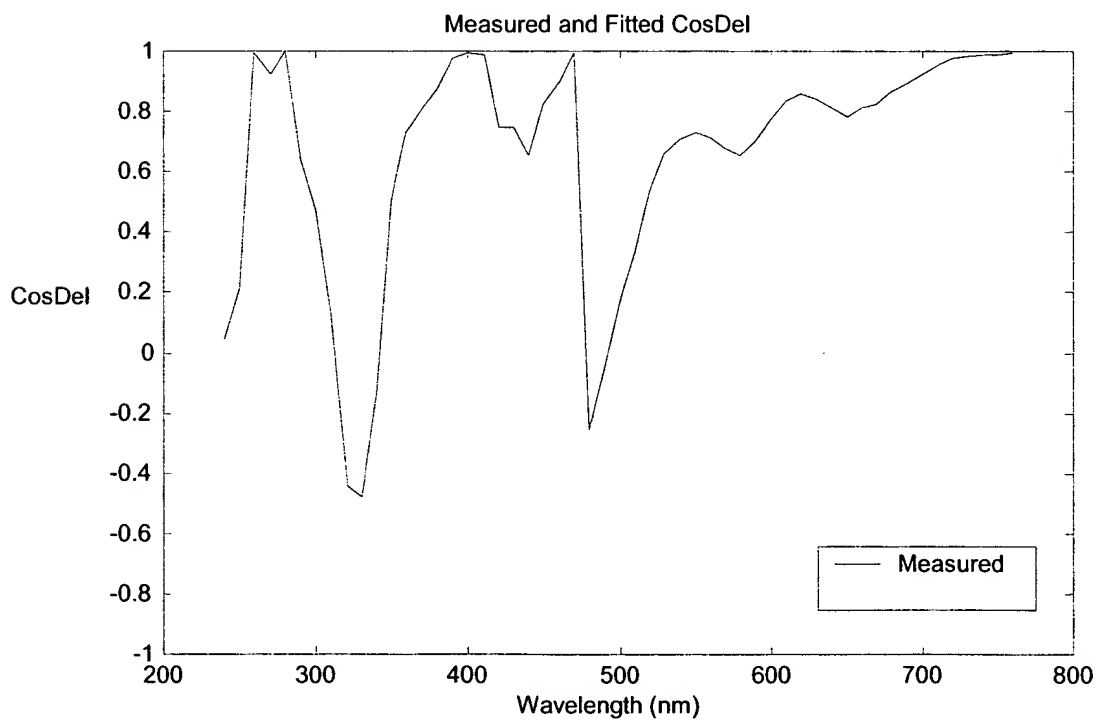
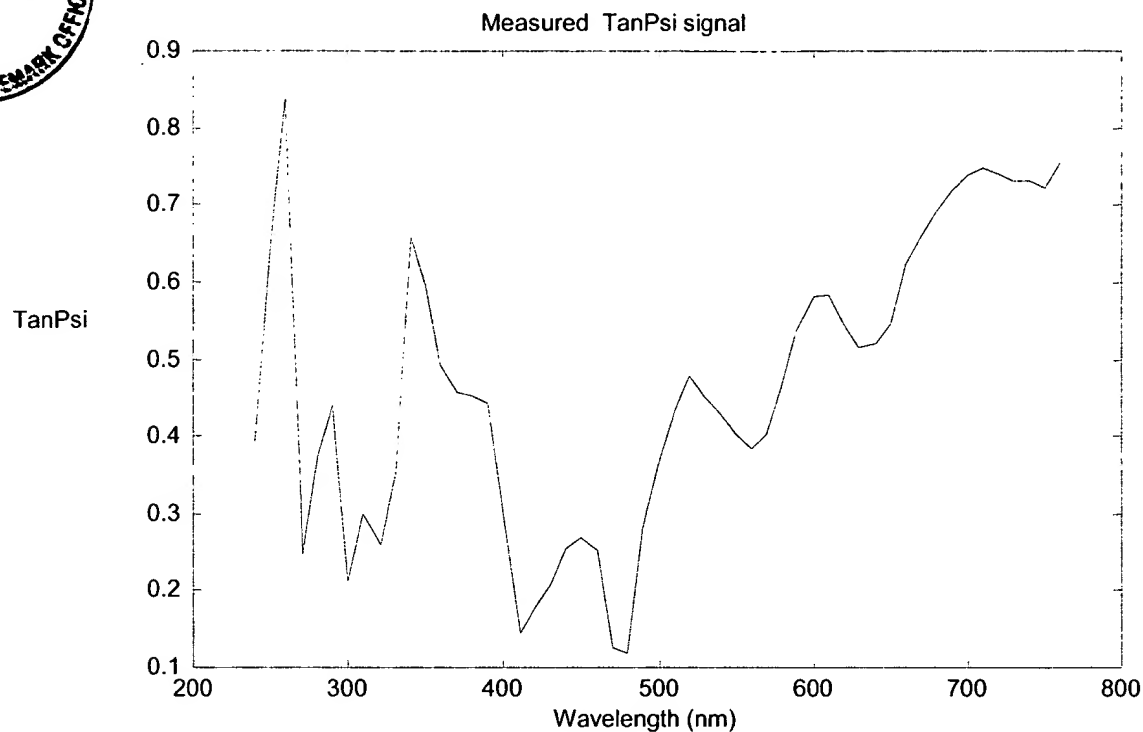


Fig. 25